



Advances in Optical Metrology

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Message from the Guest Editors

Dear Colleagues,

We are pleased to invite you to submit a manuscript to the *Photonics* Special Issue ‘Advances in Optical Metrology’.

Our scope includes all the challenges of metrology—from the optics of large space telescopes to the small optic systems of cellphone camera lenses. With regard to the methodology, this Special Issue aims to encompass methods using a Fizeau interferometer, a low coherence interferometer, frequency comb distance measurement, a physical contact profilometer, deflectometer, fringe projection, photogrammetry, and all possible methods for optical testing. As the above approaches adopt the unique mathematical model, data process modeling methods, such as dimensional data, surface reconstruction, tolerance, and error analysis, are also within the scope of this Special Issue.

The impact of this Special Issue is in providing insights into the latest challenges in optical metrology in various fields and to educate stakeholders throughout the optics community.

